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APPLICANTS

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** CONTINUING DATA ***** *TN*
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** FOREIGN APPLICATIONS ***** *TN*
 REPUBLIC OF KOREA 2002-42217 07/18/2002
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Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and Acknowledged	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance Examiner's Signature <i>TN</i> Initials	STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 15	TOTAL CLAIMS 29	INDEPENDENT CLAIMS 3
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 30593
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TITLE
 Method of forming material using atomic layer deposition and method of forming capacitor of semiconductor device using the same

☐ All Fees